

**PRECISION APERTURES FOR LITHOGRAPHIC SYSTEMS****ABSTRACT**

Aperture members are provided wherein there is thin 1-10 micrometer thick crystalline membrane that is surrounded by a frame of a bulk type crystalline material. The aperture being an opening through the membrane in a typical shape useful for device fabrication, such as a circle or pattern. The aperture member of the invention can be fabricated out of a typical silicon crystalline wafer in a process where doping in a region serves as an etch stop.

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